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## \*\* CONTINUING DATA \*\*\*\*\*

None - BC

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

JAPAN 2002-279880 09/25/2002

✓ BC

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

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Foreign Priority claimed 35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	STATE OR COUNTRY JAPAN	SHEETS DRAWING 5	TOTAL CLAIMS 32	INDEPENDENT CLAIMS 16
Verified and Acknowledged	Examiner's Signature Initials				

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## TITLE

Methods for producing silicon nitride films and silicon oxynitride films by thermal chemical vapor deposition

FILING FEE	FEES: Authority has been given in Paper	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of
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